LAM Research
490 AutoEtch Plama Etch 150mm Configuration
SN 1821

LAM Research
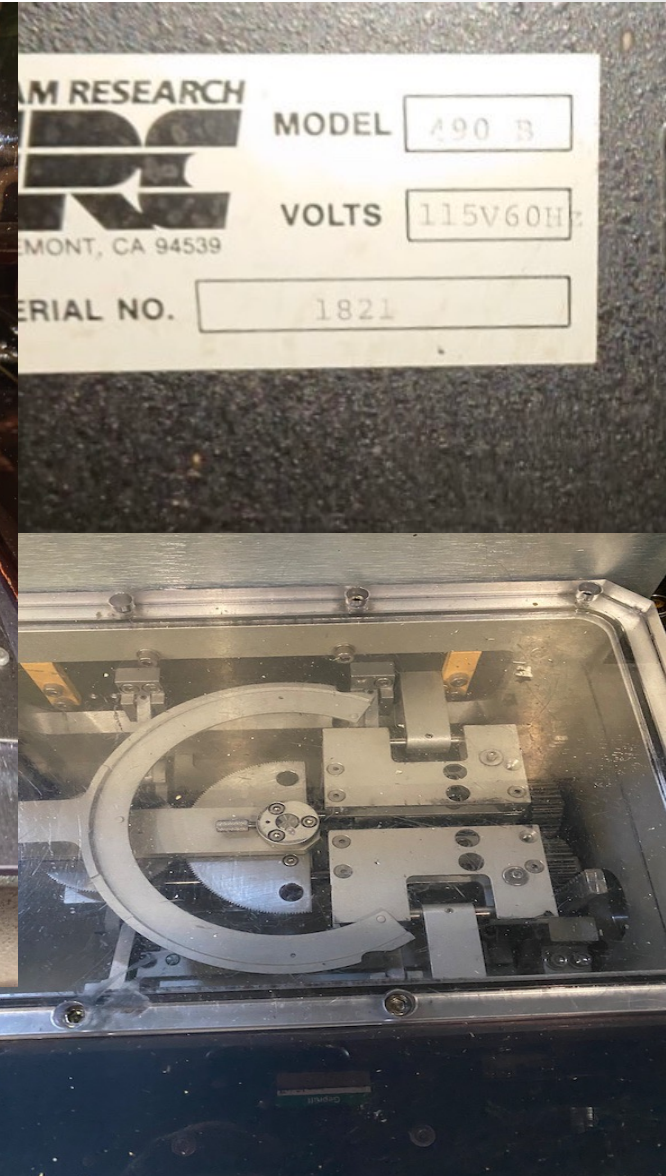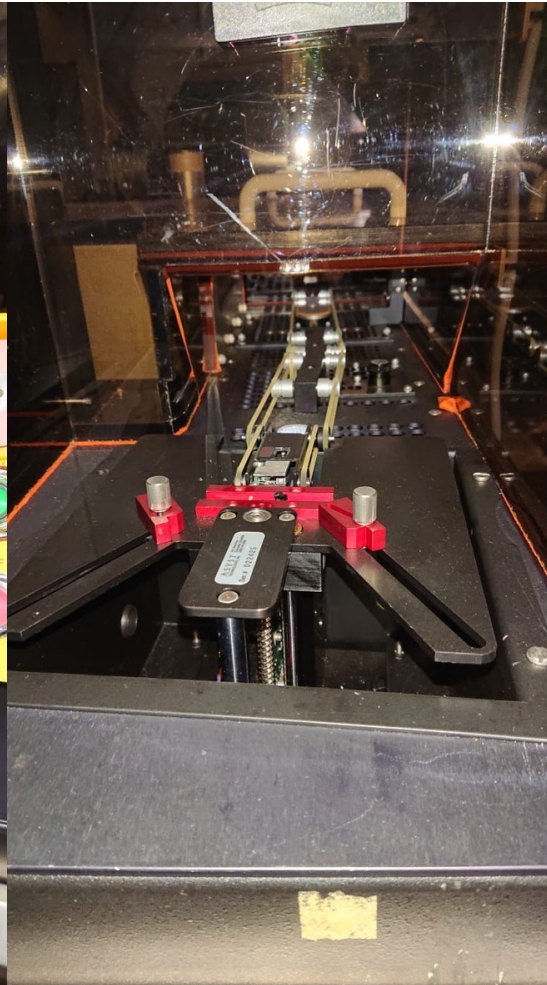# Autoetch 490 Plasma Etch

LAM 490 AutoEtcher
- Polysilicon: 490
- Wafer size: 6 inch
- Upgraded TFT monitors
- Wafer detection
- Incl maintenance console
- Conditon: AS IS (No Chiller, No pump but with ENI RF Generator)

Features:
- Single-wafer processing
- Fully automated microprocessor control
- Cassette-to-cassette wafer processing
- Vacuum load locked
- Programmable, variable electrode spacing
- Endpoint detection
- Configurable for 3-inch to 6-inch wafers
- Stand-alone or bulk-head mount configuration

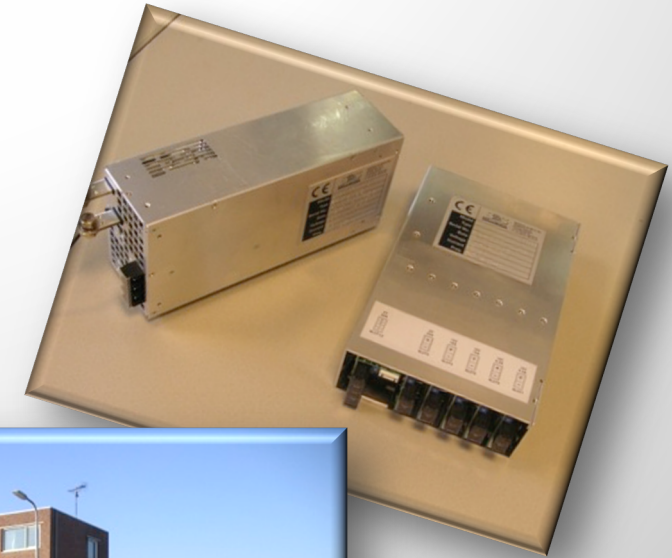**LAM Research**
Autoetch 490 Plasma Etch

Solutions on Silicon BV

Your service partner for LAM Research Equipment

- **Equipment Support**
  PM, CM, Trouble shooting, Upgrading, Training and Onsite Service Contracts

- **Process Support**
  Process design, Improvement,
  Fab-to-Fab Transfer and Integration

- **Refurbishment**
  From custom to complete refurbishment

- **Relocation**
  Auditing, Fingerprinting, Decommissioning, Installation, Acceptance

- **Materials**
  Supplier of first class second source materials